

Form PTO 1449  
(Modified)U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTY DOCKET NO.

236518US26YA

SERIAL NO.

10/673,138

## LIST OF REFERENCES CITED BY APPLICANT

APPLICANT

Andrej S. MITROVIC

FILING DATE

September 30, 2003

GROUP

2128

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	US 6,571,371	5/2003	Coss, et al.			
	AB	US 6,763,277	7/2004	Allen, et al.			
	AC	US 6,529,789	3/2003	Campbell, et al.			
	AD	US 6,628,809	9/2003	Rowe, et al.			
	AE	US 6,728,591	4/2004	Hussey, et al.			
	AF	US 6,774,998	8/2004	Wright, et al.			
	AG	US 2005/0010319	1/2005	Patel, et al.			
	AH	US 2004/0044513	3/2004	Kitahara, Noriaki			
	AI	US 6,615,097	9/2003	Ozaki, Hiroji			
	AJ	US 6,618,856	9/2003	Coburn, et al.			
	AK	US 2004/0044513	3/2004	Kitahara, Noriaki			
	AL	US 5,539,652	7/23/1996	Tegethoff			
	AM	US 6,581,029 B1	6/17/2003	Fisher			
	AN	US 2003/0003607	1/2/2003	Kagoshima et al			

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AO	CN 1335558A	2/13/2002	China (with Partial English Translation)	X	
	AP	JP 2004-527117	9/2/2004	Japan		X
	AQ	WO 03/060779 A1	7/24/2003	WIPO		X
	AR	JP 2005-515623	5/26/2005	JAPAN (With English Abstract)		X
	AS	WO 03/009345 A2	1/30/2003	WIPO		X
	AT	JP 2005-522018	7/21/2005	JAPAN (With English Abstract)		X
	AU	JP 2002-367875	12/20/2002	JAPAN		X
	AV	JP 2003-502771	1/21/2003	JAPAN		X

## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

	AW	Robert W. ATHERTON, et al., "Detailed Simulation for Semiconductor Manufacturing", Proceedings of the 1990 Winter Simulation Conference				
	AX	Angus J. MACDONALD, et al, "Integrated CAM and Process Simulation to Enhance On-Line Analysis and Control of IC Fabrication"; IEEE Transactions on Semiconductor Mfg., Vol. 3, No. 2, May 1990				
	AY	Yea-Huey SU, et al. "Conceptual Framework for Manufacturing Service Provisioning by Virtual Fabs"; 1998 NSC Republic Of China; 1998 Semiconductor Mfg. Technology Workshop				
	AZ	Chanette RASMIDATTA, et al. "New approaches for Simulation of Wafer fabrication : The Use of Control Variates and Calibration Metrics" Proceedings of 2002 Winter Simulation Conference; 2002				<input type="checkbox"/> Additional References sheet(s) attached

Examiner

Date Considered

\*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. <b>236518US26YA</b>		SERIAL NO. <b>10/673,138</b>	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT <b>Andrej S. MITROVIC</b>			
				FILING DATE <b>September 30, 2003</b>		GROUP <b>2128</b>	
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AAA	US 5,377,116	12/1994	Wayne, et al.			
	AAB	US 5,629,877	5/1997	Tamegaya, Yukio			
	AAC	US 6,625,497	9/2003	Fairbairn, et al.			
	AAD	US 6,185,472	2/6/2001	Onga, et al.			
	AAE						
	AAF						
	AAG						
	AAH						
	AAI						
	AAJ						
	AAK						
	AAL						
	AAM						
	AAN						
<b>FOREIGN PATENT DOCUMENTS</b>							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AAO	JP 2003-17471	1/17/2003	JAPAN (With English Abstract)			X
	AAP	WO 02/065511 A2	8/22/2002	WIPO			X
	AAQ	JP 2004-524685	8/12/2004	JAPAN			X
	AAR	WO 02/069063 A2	9/6/2002	WIPO			X
	AAS	JP 2004-531878	10/14/2004	JAPAN			X
	AAT						
	AAU						
	AAV						
	AAW						
<b>OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)</b>							
	AAX	Naomi YONEMURA, et al. "Heat Analysis on Insulated Metal Substrates", 1996, IEEE, pgs. 1407-1410					
	AAY	Tony C. MIDEA, et al., "Casting Simulation Software Survey", 1999, pages 1-4					
	AAZ	Heru SETYAWAN, et al. "Visualization and numerical simulation of fine particle transport in a low-pressure parallel plate chemical vapor deposition reactor", Chemical Engineering Science 57 (2002) pages 497-506					
							<input type="checkbox"/> Additional References sheet(s) attached
Examiner					Date Considered		
<small>*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

Form PTO 1449  
(Modified)U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY DOCKET NO.  
236518US26YASERIAL NO.  
10/673,138

## LIST OF REFERENCES CITED BY APPLICANT

APPLICANT  
Andrej S. MITROVICFILING DATE  
September 30, 2003GROUP  
2128

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AAAA	US 7,047,095 B2	5/16/2006	Tomoyasu			
	AAAB	US 6,587,744 B1	7/1/2003	Stoddard, et al.			
	AAAC						
	AAAD						
	AAAE						
	AAAF						
	AAAG						
	AAAH						
	AAAI						
	AAAJ						
	AAAK						
	AAAL						
	AAAM						
	AAAN						

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AAAO	JP 2000-517473	12/26/2000	JAPAN (With English Abstract)		X
	AAAP	WO 03/058699 A1	7/17/2003	WIPO		X
	AAAQ	JP 2005-514790	5/19/2005	JAPAN (With English Abstract)		X
	AAAR					
	AAAS					
	AAAT					
	AAAU					
	AAAV					
	AAAW					
	AAAX					

## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

	AAAY	
	AAAZ	
		<input type="checkbox"/> Additional References sheet(s) attached

Examiner

Date Considered

\*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.